



RICHARD V. BURGUJIAN

202.408.4024

RICH.BURGUJIAN@finnegan.com



December 27, 2001

ATTORNEY DOCKET NO. 04329.2722
CUSTOMER NO. 22,852



Box PATENT APPLICATION
Assistant Commissioner for Patents
Washington, DC 20231

New U.S. Patent Application

Title: GAS CIRCULATING-PROCESSING APPARATUS

Inventors:

Hiroshi KUBOTA et al.

Rempei NAKATA

Naruhiko KAJI

Itsuko SAKAI

Takashi YODA

Addresses:

Yokohama-shi, Japan

Kamakura-shi, Japan

Kamakura-shi, Japan

Yokohama-shi, Japan

Machida-shi, Japan

Sir:

We enclose the following papers for filing in the United States Patent and Trademark Office in connection with the above patent application.

1. Application- 52 pages, including 4 independent claims and 20 claims total.
2. Drawings- 7 sheets of drawings containing 14 Figures.
3. Certified copy of Japanese Patent Application Nos. 2000-400833, filed December 28, 2000, 2000-401179, filed December 28, 2000, and 2000-401180 filed December 28, 2000.
4. The filing fee is calculated as follows:

Assistant Commissioner for Patents
December 27, 2001
Page 2

Basic Application Filing Fee					\$740	\$ \$740.00
	Number of Claims		Basic	Extra Claims		
Total Claims	20	-	20		x \$18	
Independent Claims	4	-	3		x \$84	\$ 84.00
<input type="checkbox"/> Presentation of Multiple Dep. Claim(s)					+\$280	
Subtotal						\$ \$824.00
Reduction by 1/2 if small entity						-
TOTAL APPLICATION FILING FEE						\$ \$824.00

6. A check for \$824.00 is enclosed. The fee includes:

\$740.00 filing fee; and
\$ 84.00 additional claims fee

This application is being filed under the provisions of 37 C.F.R. § 1.53(f).
Applicants await notification from the Patent and Trademark Office of the time set for
filing the Declaration.

Applicants claim the right to priority based on Japanese Patent Application Nos.
2000-400833, filed December 28, 2000, 2000-401179, filed December 28, 2000, and
2000-401180 filed December 28, 2000.

Please address all correspondence with respect to this application to:

Finnegan, Henderson, Farabow,
Garrett & Dunner, L.L.P.
1300 I Street, N.W.
Washington, D.C. 20005-3315

Please accord this application an application number and filing date.

RVB/FPD/sem
Enclosures[illegible]